

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>		Docket Number (Optional) TWI-31500	Application Number 09/938,415
		Applicant(s) Kenneth C. Johnson et al.	
		Filing Date August 23, 2001	Group Art Unit 2851

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
AS	AA	5,867,276	02/02/1999	McNeil et al.	356	445	03/07/1997
AS	AB	5,963,329	10/05/1999	Conrad et al.	356	372	10/31/1997

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	No

OTHER DOCUMENTS
(Including Author, Title, Date, Pertinent Pages, Etc.)

AS	AC	J. Allgair et al., "Manufacturing Considerations for Implementation of Scatterometry for Process Monitoring," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 135-134.
AS	AD	J.Bao et al., "Specular Spectral Profilometry on Metal Layers," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 882-892.

Examiner	Date Considered
<i>AS</i> Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	